



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No.10/733,201
Filing DateDecember 9, 2003
Confirmation No.5994
Inventor..... Garo J. Derderian et al.
AssigneeMicron Technology, Inc.
Group Art Unit1762
Examiner Kelly M. Stouffer
Attorney's Docket No. MI22-2402
Customer No. 021567
Title: Atomic Layer Deposition Method of Depositing an Oxide on a
Substrate

RESPONSE TO AUGUST 31, 2006 OFFICE ACTION

To: Mail Stop Amendment
Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

VIA U.S. EXPRESS MAIL

From: Mark Matkin (Tel. 509-624-4276; Fax 509-838-3424)
Wells St. John P.S.
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Responsive to the Office Action dated August 31, 2006, Applicant
amends and remarks as follows:

AMENDMENTS

12/04/2006 CCHAU1 00000021 10733201

01 FC:1202 150.00 OP
02 FC:1201 1200.00 OP